

Low Pressure Plasma System



Applications

- **Cleaning of surfaces**
(e.g. before bonding, soldering or gluing)
- **Activation of surfaces**
(e.g. before printing, varnishing or gluing)
- **Etching of surfaces**
(e.g. before microstructuring of silicon or etching of PTFE)
- **Deposition of surfaces - plasmopolymerization**
(e.g. deposition of hydrophobic / hydrophilic layers)

Technical Data

- 1. Switch cabinet:**
W 550 mm (22") x H 330 mm (13") x D 500 mm (20")
Weight: approx. 30 kg (without pump)
- 2. Plasma chamber:**
Pico: Ø 150 mm, L 320 mm (stainless steel recipient)
Pico UHP: Ø 130 mm, L 300 mm (glass recipient)
Chamber volume: approx. 5 litres / 4 litres
- 3. Gas connection:**
2 pcs. gas channels controlled with needle valves
- 4. Plasma power supply:**
40 kHz / 200 W, infinitely variable
- 5. Electrodes and trays:**
1 pc. electrode and 1 pc. tray
- 6. Electric control:**
Semi automatic, process timer
- 7. Connections:**
Gas: 6 mm Swagelok
Power supply: 110 - 120 V or 220 - 240 V AC / 50 - 60 Hz
Exhaust tube: Ø 10 mm
- 8. Vacuum pump:**
Rotary vane pump, suction power: 2,5 m³/hr
Pump is able to run with O₂



Plasma system Pico:
back side

Applications

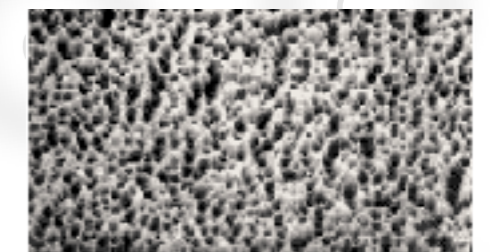
- Analysis (SEM, TEM)
- Archaeology
- Medical technology
- Optics
- Plastics industry
- Research and development
- Semiconductor industry
- Small scale manufacturing
- Textile treatment
- ...

Options / Accessories

- 13.56 MHz generator
- 2.45 GHz generator (microwave)
- Recipient: quartz- or borosilicate glass
- Corrosive gas version
- Fully automatic control
- Heating plate
- Mass-Flow-Controller
- PC control
- Polymerization accessories
- RIE electrode
- Rotary drum
- Spare parts kit
- ...



PTFE surface: before plasma treatment



PTFE surface: after plasma treatment

Find us on the internet at:

www.plasma.de